

Docket Number: 081468-0306524  
Client Reference: P-0381.020-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

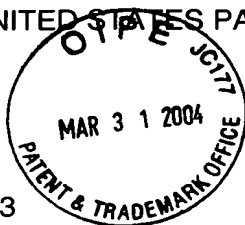
In Re the Application of

JOERI LOF et al.

Application No.: 10/705,783

Filed: November 12, 2003

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD



Group Art Unit:

Examiner:

Confirmation No.:

**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO-1449 to Applicants with the next Office communication to indicate that the references have been considered, per MPEP § 609.

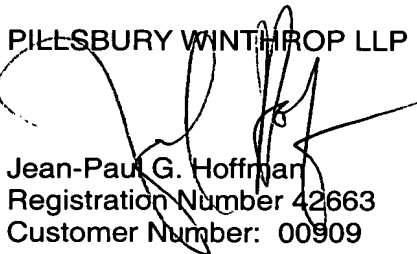
The undersigned respectfully notes that copies of U.S. references are not required in applications filed after June 30, 2003

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

PCT/WO99/49504, the U.S. counterpart of EP 0 605 103 (US 5,610,683) and US 4,480,910, cited in the attached Search Report, were already submitted for consideration by the Examiner on November 12, 2003.

Respectfully Submitted,

PILLSBURY WINTHROP LLP

  
Jean-Paul G. Hoffman  
Registration Number 42663  
Customer Number: 00909

Date: March 31, 2004

P.O. Box 10500  
McLean, VA 22102  
Telephone: (703) 905-2000  
Facsimile: (703) 905-2500

FORM PTO-1449 (modified)  
 To: U.S. Department of Commerce  
 (PW FORM PAT-1449)  
 Patent and Trademark Office

Atty.  
Dkt. No.

M#

Client Ref.

081468

0306524

P-0381.020-US

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Joeri LOF et al.

Appln. No.: 10/705,783

Filing Date: November 12, 2003

Examiner: Unassigned

Group Art Unit: Unassigned

Date: March 31, 2004

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of

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## U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR					
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					

## FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	IR	JP 07-132262	05/1995	Japan	Hirakawa et al.	X		
	JR	JP 58-202448	11/1983	Japan	Kawamura et al.	X		
	KR	WO 2004/019128	03/2004	PCT	Omura et al.			
	LR	WO 03/077036	092003	PCT	Schuster	X		
	MR							
	NR							
	OR							
	PR							
	QR							
	RR							

## OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

SR	Copy of European Search Report for EP Application No. 02257822.3 dated January 20, 2004			
TR	S. Owa et al., "Update on 193nm immersion exposure tool", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-51			
UR	H. Hata, "The Development of Immersion Exposure Tools", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-22			
VR	T. Matsuyama et al., "Nikon Projection Lens Update", SPIE Microlithography 2004, 5377-65, March, 2004			
WR	"Depth-of-Focus Enhancement Using High Refractive Index Layer on the Imaging Layer", IBM Technical Disclosure Bulletin, Vol. 27, No. 11, April 1985, p. 6521			
XR	A. Suzuki, "Lithography Advances on Multiple Fronts", EEdesign, EE Times, January 5, 2004			
YR				

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.